

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-713		SERIAL NO. 08/886,388	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Gurje S. Sandhu et al.			
					FILING DATE Filed herewith		GROUP 2811	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
SWC	AA	4,558,509	12/1985	Tiwari				
	AB	4,568,565	2/1986	Gupta et al.				
	AC	5,023,683	6/91	Yamada			RECEIVED 99 APR 13 PM :29 TECHNOLOGY CENTER JUL 2 1990	
	AD	5,053,351	10/91	Fazan et al.				
	AE	5,071,781	12/91	Seo et al.				
	AF	5,130,172	7/92	Hicks et al.				
	AG	5,139,825	8/92	Gordon et al.				
	AH	5,168,073	12/92	Gonzalez et al.				
	AI	5,216,267	6/93	Jin et al.				
	AJ	5,223,729	6/93	Kudoh et al.				
SWC	AK	5,290,726	3/94	Kim				
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		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AN							
	AO							
	AP							
OTHER PRIOR ART (including Author, Title, Date, Pertinent Pages, Etc.)								
SWC	AR		Conrad, J.R. et al., "Ion Beam Assisted Coating And Surface Modification With Plasma Source Ion Implantation", J. Vac. Sci. Technol. A 8 (4), Jul/Aug. 1990, 3146-3151					
SWC	AS		Temmler, D., "Multilayer Vertical Stacked Capacitors (MVSTC) for 64 Mbit and 256 mBit DRAMs", Article, Institute of Semiconductor Physics, Germany, no date, 2 pgs.					
SWC	AT		Niemer, B., et al., "Organometallic Chemical Vapor Deposition of Tungsten Metal, and Suppression of Carbon Incorporation by Codeposition of Platinum", Article, University of California, Los Angeles, CA, Dept. of Chemistry and Biochemistry, published 8/4/92, 3 pgs.					
EXAMINER	CRANE			DATE CONSIDERED		6/18/99		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

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*Examiner Initial		Document Number	Date						
SWC	AA	5,300,321	4/94	Nakano et al.				SEARCHED <i>SO APR 19 65</i>	
	AB	5,320,878	6/94	Maya				INDEXED <i>BY 3 17</i>	
	AC	5,330,614	7/94	Ahn				CITED <i>CH 1 A</i>	
	AD	5,403,620	4/95	Kaesz et al.				MAILED <i>PER 1:22</i>	
	AE	5,508,218	4/96	Jun				RECD <i>2000</i>	
	AF	5,006,481	04/91	Chan et al.		437	52		
	AG	5,021,357	06/91	Taguchi et al.		437	52		
	AH	5,061,651	10/91	Ino		437	52		
	AI	5,116,776	05/92	Chan et al.		437	52		
	AJ	5,135,883	08/92	Bae et al.		437	52		
SWC	AK	5,164,337	11/92	Ogawa et al.		437	228		
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SWC	AR		T. Morihara et al., "Disk-Shaped Stacked Capacitor Cell for 256 Mb Dynamic Random-Access Memory", Aug. 19, 1994.						
			Jpn. J. Appl. Phys. Vol. 33 (1994), Pt. 1, No. 8, pp. 14-19						
SWC	AS		S. Woo et al., "Selective Etching Technology of in-situ P Doped Poly-Si (SEDOP) for High Density DRAM Capacitors",						
			1994 Symposium on VLSI Technology Digest of Technical Papers, pp. 25-26						
SWC	AT		H. Watanabe et al., "Stacked Capacitor Cells for High-density dynamic RAMs", IEDM 1988, pp. 600-603						
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SWL	AA 5,170,233	12/92	Liu et al.		257	308		
SWL	AB 5,622,882	04/97	Yee		438	210		
SWL	AC 5,631,184	05/97	Ikemasu et al.		438	397		
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
	AJ							
	AK							
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							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
SWL	AR		Inoue, S., et al., "A Spread Stacked Capacitor (SCC) Cell for 64MBIT DRAMs", IEEE 1989, pp. 31-34 (2.3.1 - 2.3.4).					
	AS							
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